

# Status of the Large Area Microchannel Plate Photodetector Project

for the Large Area Picosecond Photodetector Development Collaboration

Bob Wagner, Argonne National Laboratory

DOE Site Review

Wednesday 25 May 2011

# LAPPD Project Scope

## Large, Cheap, Fast Microchannel Plate Photomultiplier

- ▶  $20 \times 20$  cm<sup>2</sup> active area (development on 3.3cm diam. disk)
- ▶ Novel, inexpensive MCP substrate
  - Borofloat glass capillary substrates (20–40μm pores, L/D ~60–40)
- ▶ Pore activation via Atomic Layer Deposition (ALD)
  - Separate material for resistive and secondary emission layers
  - Optimize resistive and emissive layers via study of range of materials
- ▶ Customized anode readout
  - Strip line double-ended readout for picosecond timing & water Cherenkov
  - Pad readout for energy and/or coarse spatial resolution -- gamma-ray telescope camera, dual readout calorimeters, medical imaging
- ▶ High quantum efficiency photocathode ---  $\geq 25\%$  (1<sup>st</sup> gen.  $> 10\%$ )
  - Alkali (baseline), multialkali
  - “III–V” materials, e.g. GaAs, GaN
  - Systematic program of photocathode development and analysis
- ▶ Waveform sampling switched capacitor array ASIC for readout
- ▶ Use simulation to vet and tune design

## Large Area Picsecond Photodetector Collaboration

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- 2 National Labs
- 3+ Universities
- 5 Divisions at Argonne
- 3 US small companies;
- Electronics expertise at Universities of Chicago and Hawaii

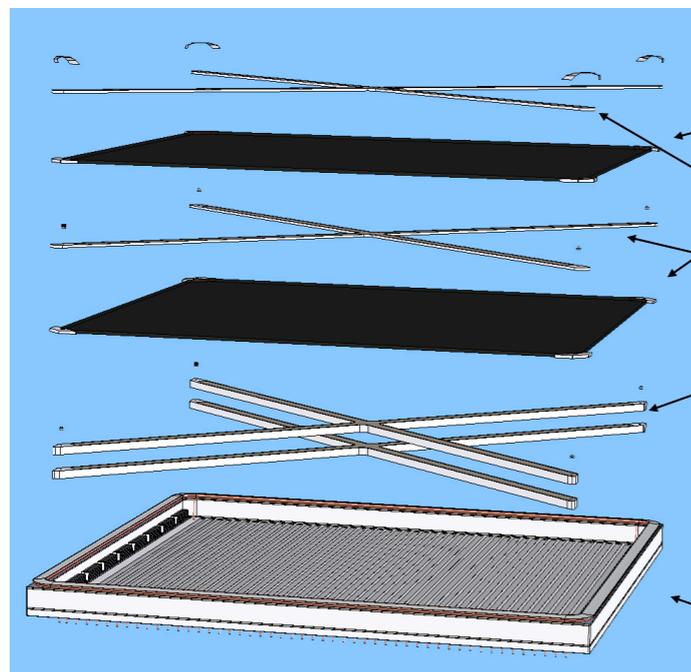
## Goals:

- **Exploit advances in material science and nanotechnology to develop new, batch methods for producing cheap, large area MCPs.**
- **Develop path to a commercializable product on a three year time scale (approaching the end of year 2 – this summer)**



# Parallel MCP-PMT Designs -- The Portfolio of Risk

- ▶ Two Complementary Designs for Photodetector
  - Ceramic packaging, evaporative photocathode -- SSL/Berkeley
    - Proven in years of fabrication in small format – high confidence of success
    - More expensive body fabrication
    - >Time/Tube construction – verify success at each step
  - All-Glass packaging, novel photocathode fabrication -- Argonne, U. Chicago
    - New design, needs development of most fabrication techniques
    - Less expensive borosilicate glass packaging
    - Target rapid production of multiple units



Ceramic body & spacers - SSL

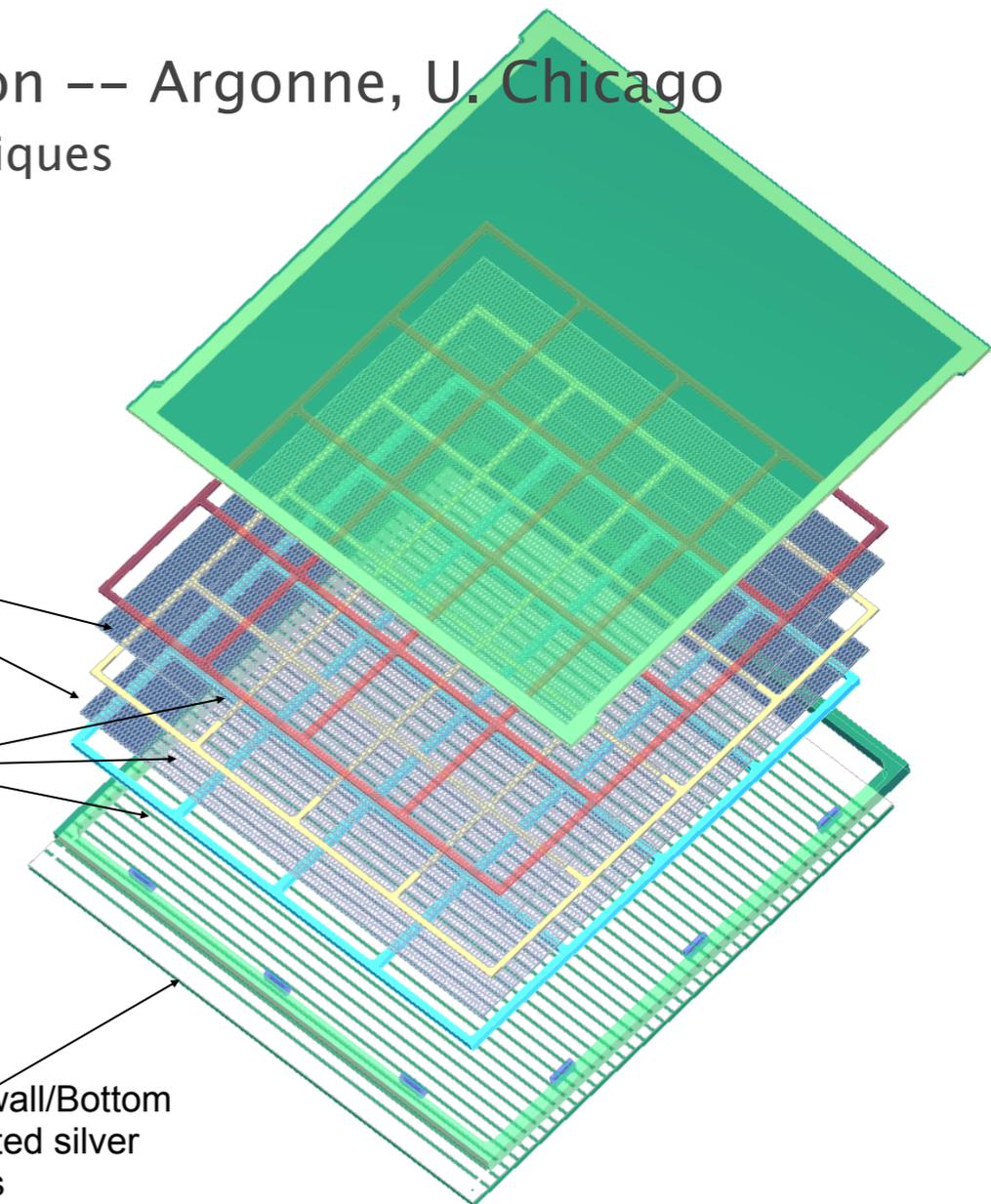
Micro-Channel Plates common to both designs

Ceramic Cross Spacers

Ceramic Sidewall/Bottom with embedded strip line. Copper chan. for indium seal

Glass Grid Spacers

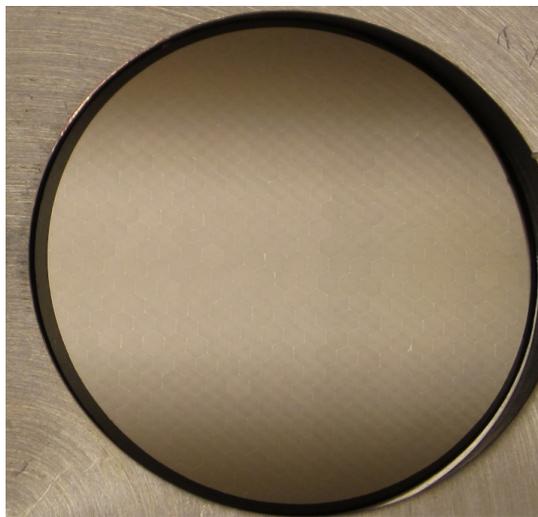
Glass Sidewall/Bottom Screen printed silver anode strips



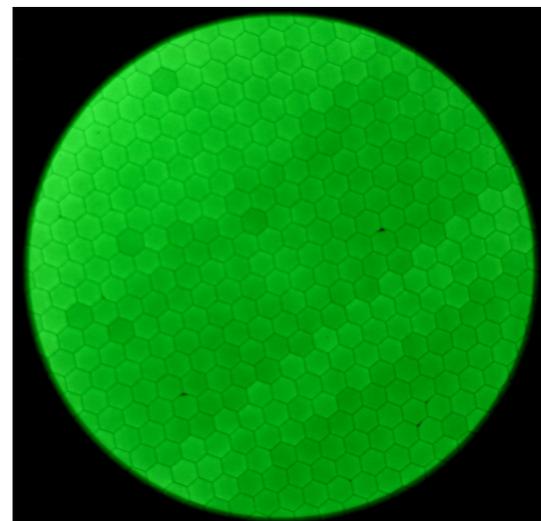
Borosilicate glass body & spacers - Argonne/UC

# Micro-Channel Plate Development Status

- ▶ Glass capillary array quality has been dramatically improved
  - Extensive development work by Incom, Inc.
- ▶ ALD functionalization has established baseline process. Materials development continuing
  - Chemistry #2 resistive layer;  $\text{Al}_2\text{O}_3$  or  $\text{MgO}$  secondary emissive layer
  - Alternative ALD materials studies planned for secondary emission
  - Tuning of process technique ongoing
- ▶ Electroding at Fermilab & SSL
  - Fermilab routinely coating multiple 33mm disks/run
  - Small numbers of 8" plates at SSL; Fermilab completing 8" evaporation chamber

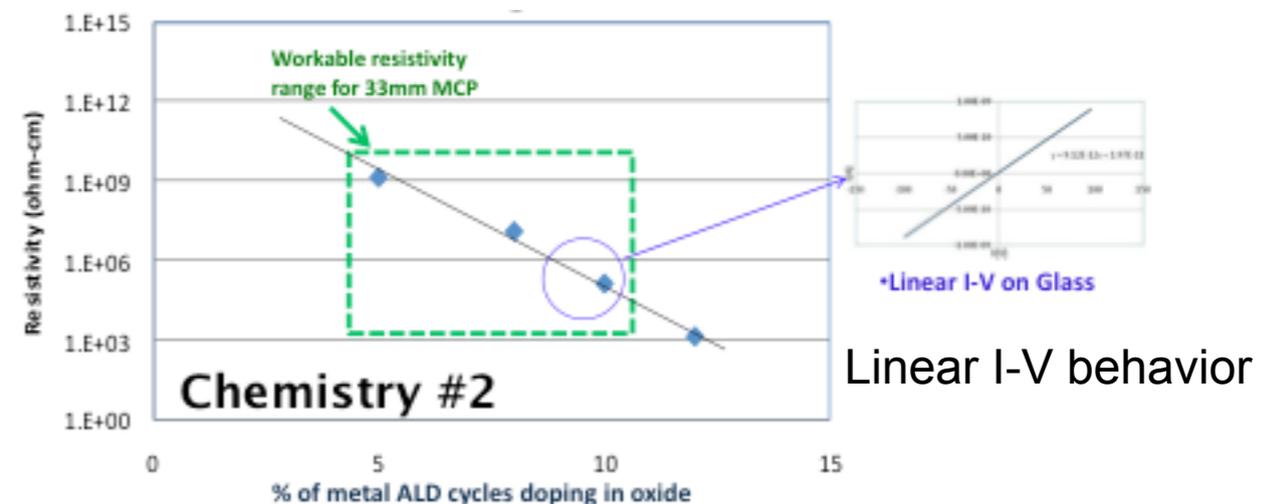


Photograph



Phosphor Image

Latest batch of 33mm capillary disks



Resistance vs. ALD Doping Cycles for Chemistry #2

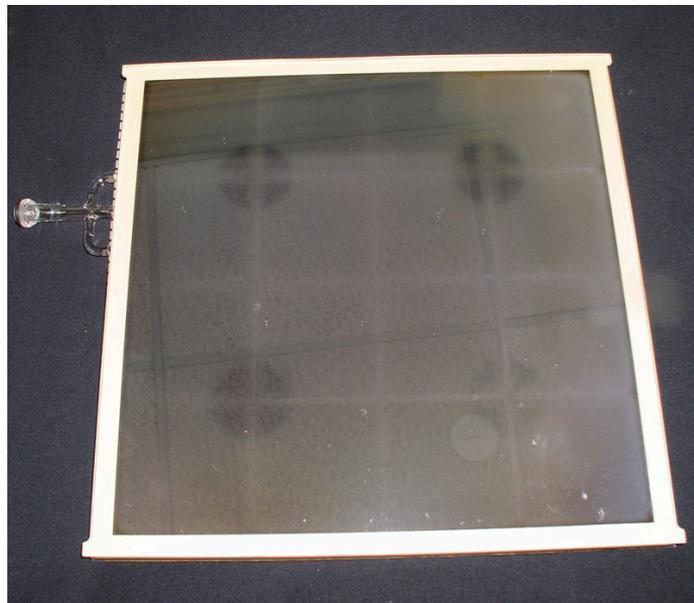
# Hermetic Packaging Status

## ▶ All-Glass Packaging

- Fabricated one sealed box with internals (dummy MCPs)
- Mock Tile fabricated with 4 working 33mm MCP pairs
  - Successful initial pump down showing leak tight seal
  - Crack in top plate developed during extended vacuum pumping for electrical testing
- Thermopressure indium seal in development

## ▶ Ceramic Packaging

- Most pieces for body assembly in hand
- Indium seal standard, although larger than past
- 8" fabrication chamber nearing completion



Mock Tile detector after final top plate frit firing



Deflection of Mock Tile top plate at vacuum

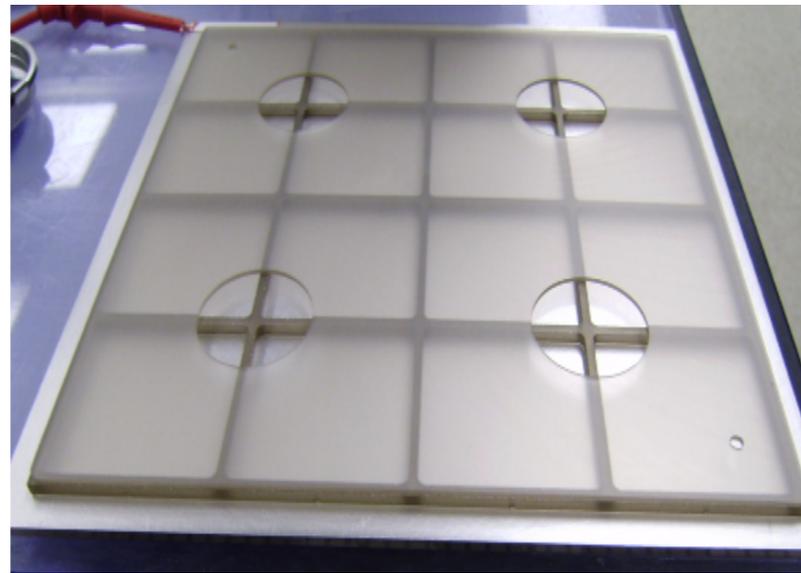


Ceramic body illustrative stack-up

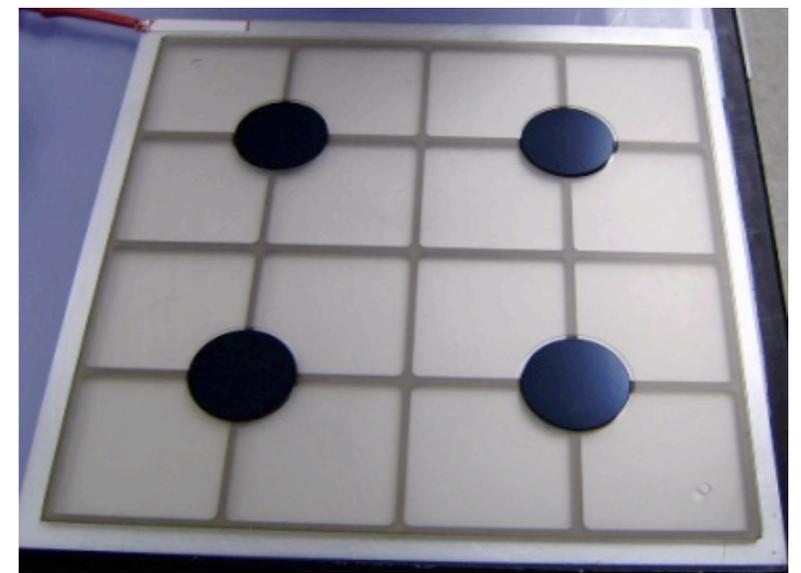
# Mock Tile Fabrication -- Assembly



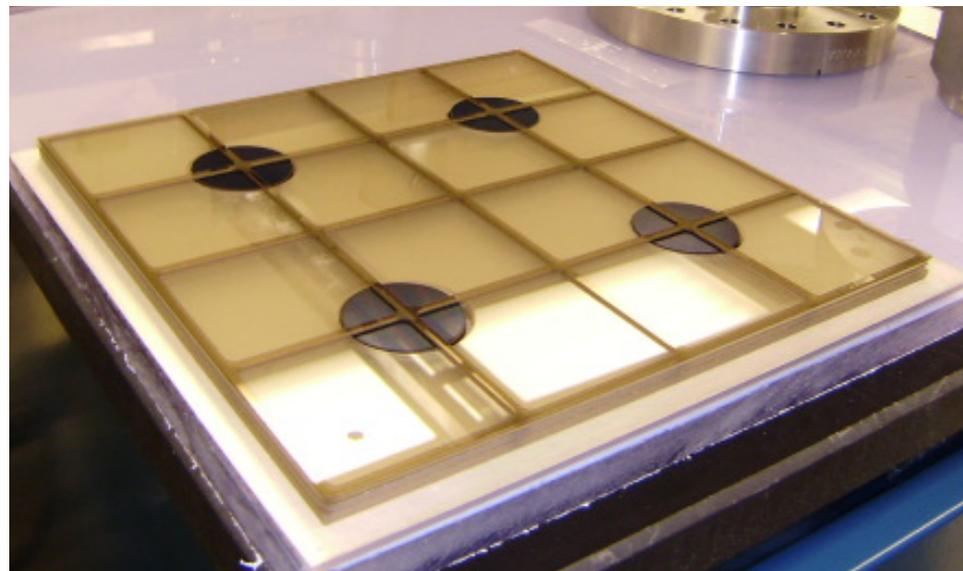
2.97mm bottom Grid Spacer



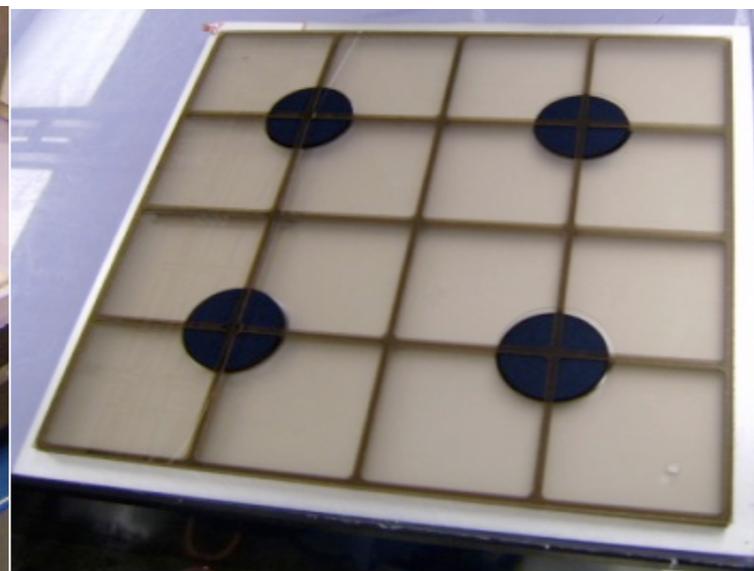
Add Mock MCP



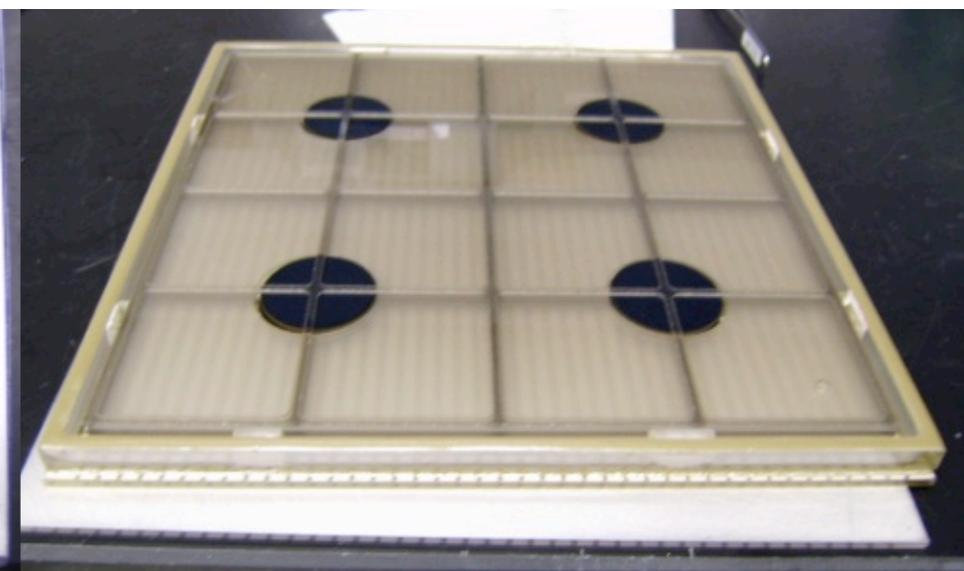
Add 33mm Functionalized MCPs



Add 1.1mm Grid Spacer



Add Mock MCP,  
33mm MCPs and top  
1.1mm Grid Spacer



Full stack in Tile Base

# Photocathode Status

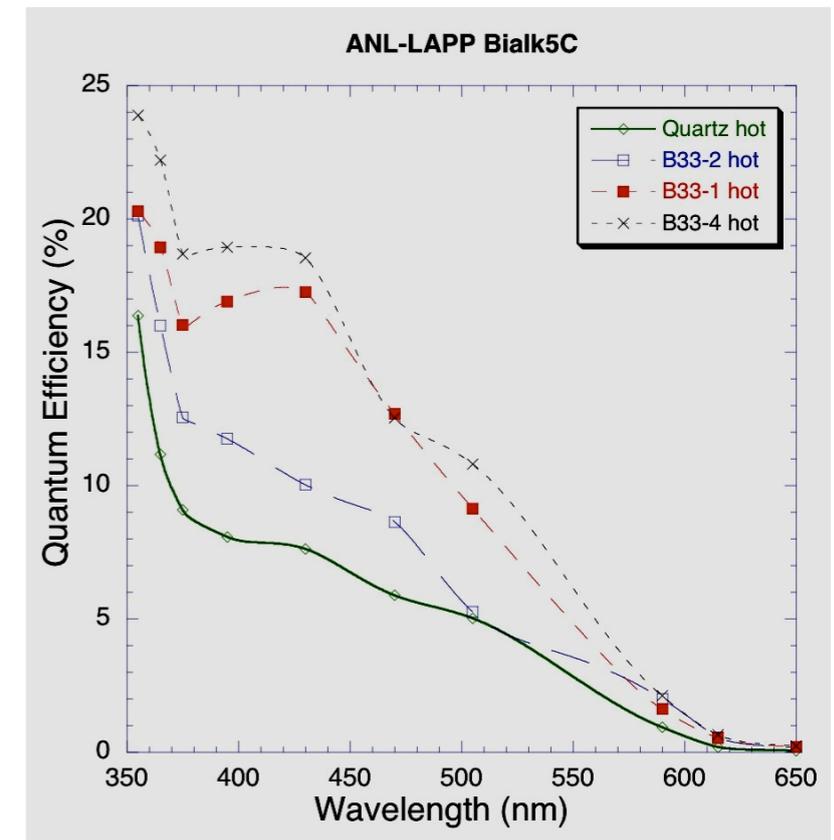
- ▶ “Shooting” bialkali photocathode samples at SSL
  - Have obtained 25% QE on borosilicate glass
- ▶ Photocathode techniques progressing well at Argonne
  - Produced first photocathode on small test PMTs using Burle equipment
  - Development vessel (Chalice) for 4”×4” photocathode using Burle equipment well advanced



**Photocathode fabrication with Burle equipment at Argonne**



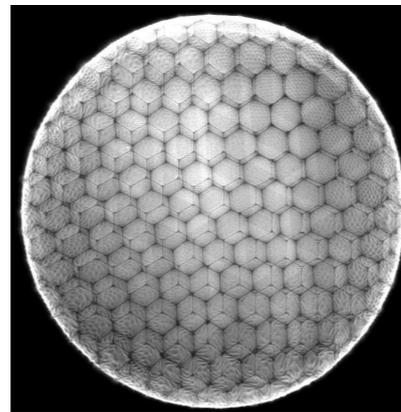
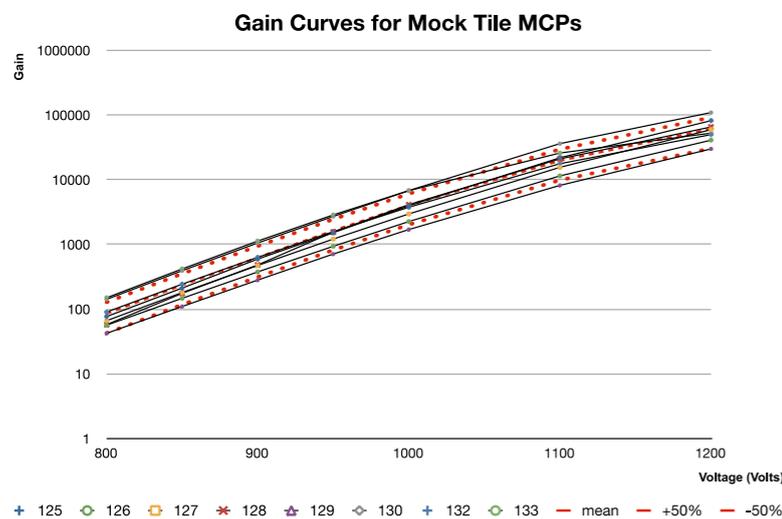
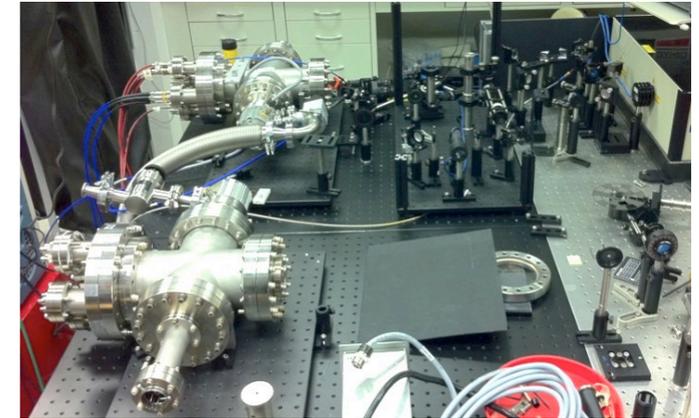
**Chalice for 4”×4” photocathode test pieces**



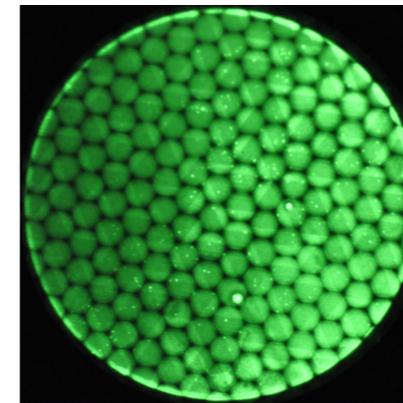
**Run #5 test KCsSb Bialkali Cathodes at SSL**

# MCP Testing Status

- ▶ UV laser setup at Argonne APS
  - Two test stations for 33mm MCPs
  - 8" plate test chamber nearing completion
  - Routinely testing 33mm MCPs for gain, stability, timing, pair configurations
- ▶ Dual test station at SSL for 33mm MCPs
  - Crossed strip delay readout + phosphor readout
  - 8" test station ready



Pair MCP XDL Image at SSL

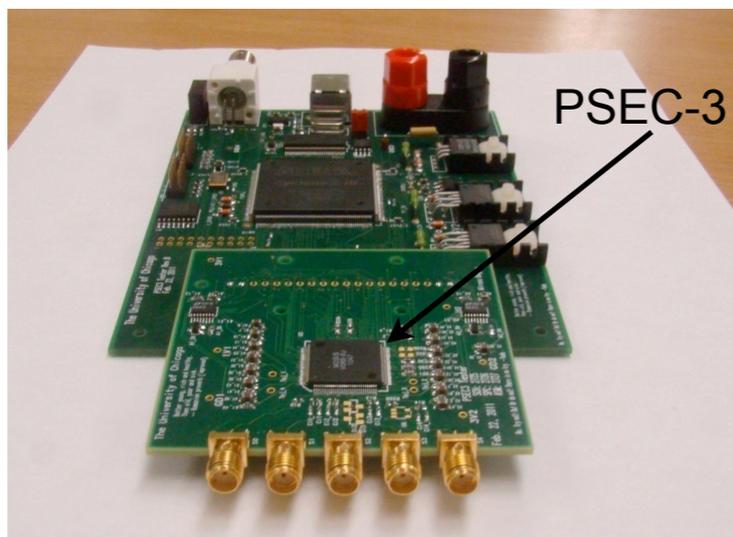
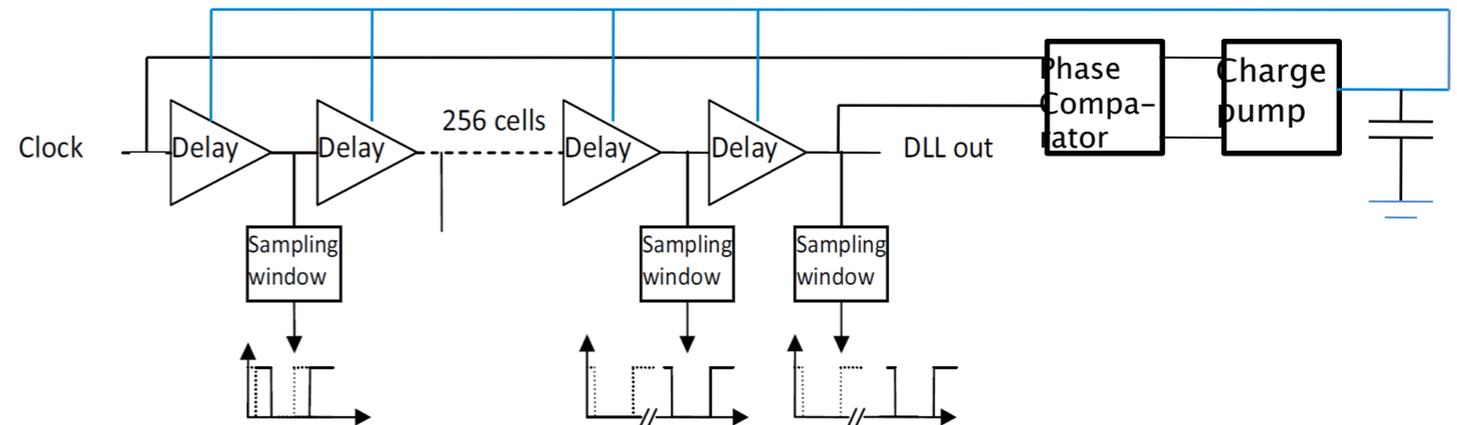


Single MCP Phosphor Image at SSL

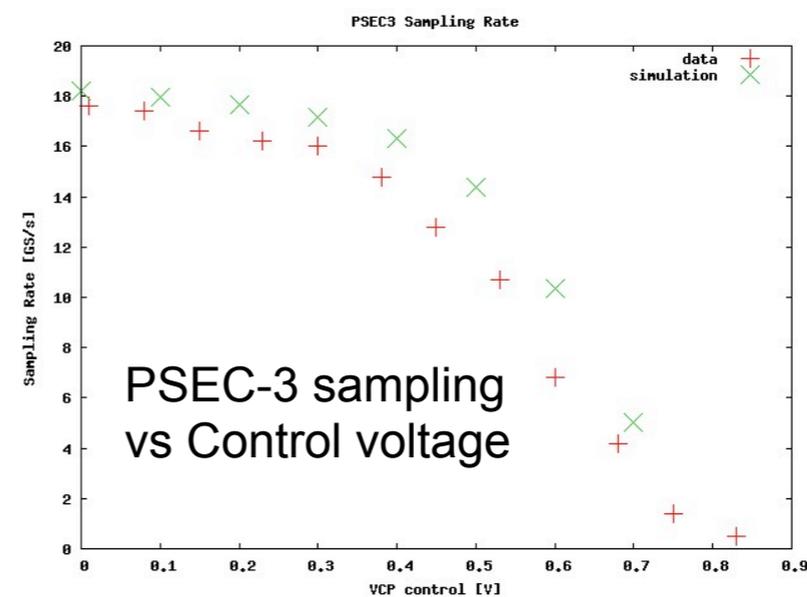
Gain curves as measured at Argonne laser test station

# Electronics Readout

- ▶ Switched capacitor array waveform sampling ASIC
  - digitize on chip; 12 bit ADC
  - >10 GSa/s capability
  - Analog bandwidth > 1 GHz
  - Event rate ~ 100 kHz
- ▶ PSEC-3
  - 4 channel
  - Submitted 11 Aug 2010, 40 pieces delivered 16 Dec 2010
  - Addressed several issues with generation 2 PSEC
- ▶ PSEC-4
  - 6 channel; two test channels converted to readout
  - Submitted 9 May 2011 to MOSIS
  - Improve analog bandwidth



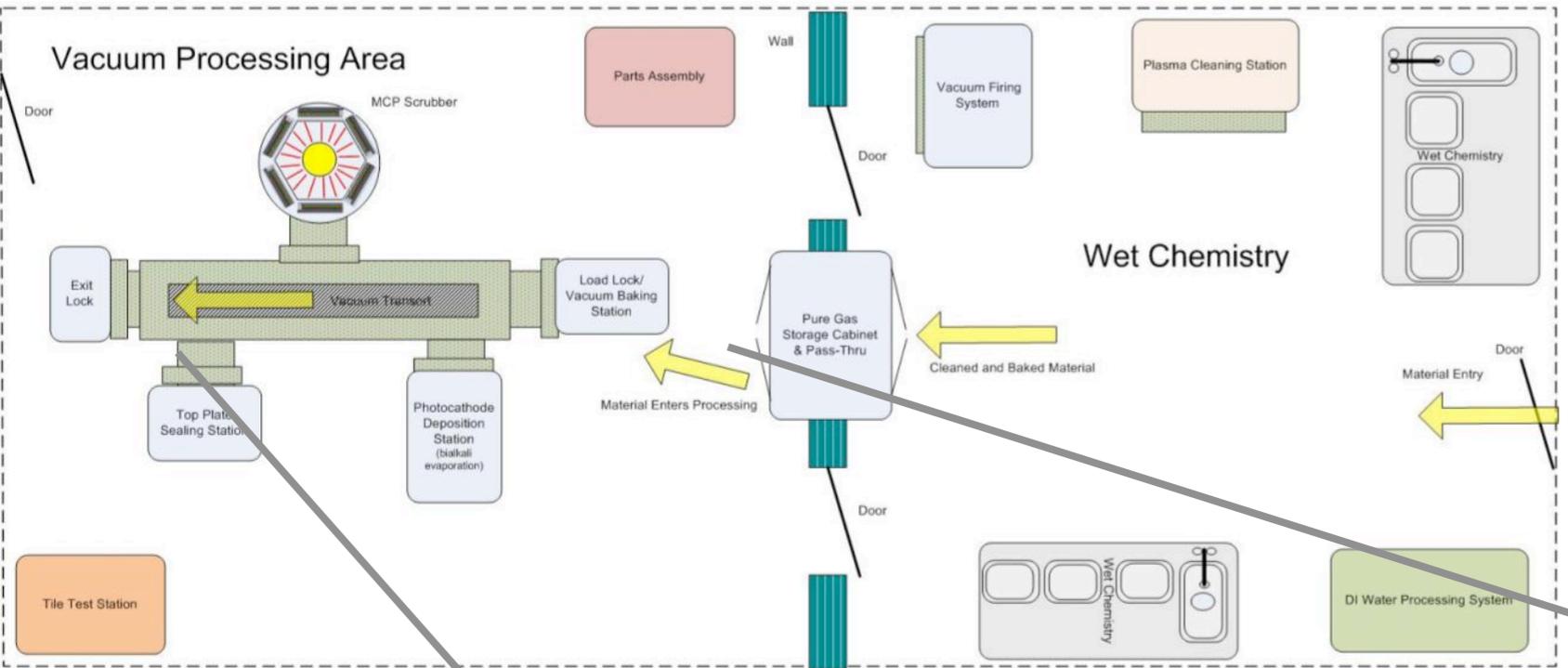
PSEC-3 Evaluation Board



Status of Large Area MCP Photodetector Project, R. Wagner, Argonne, DOE Review, 20110525

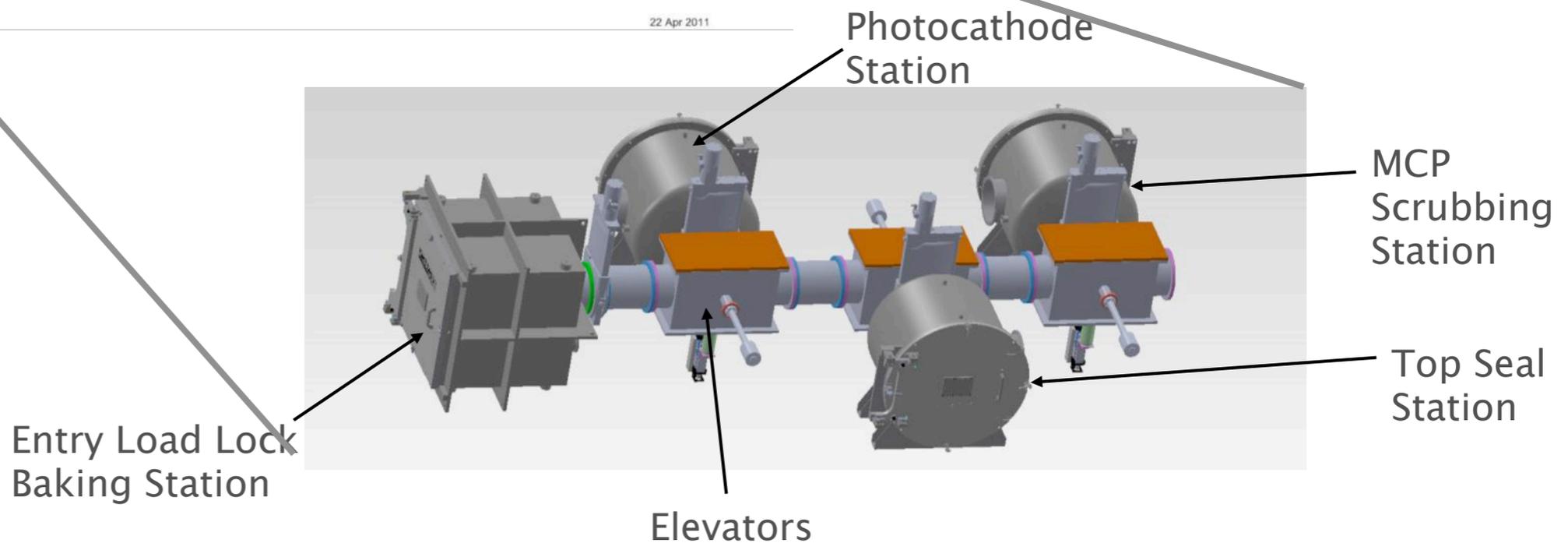


# MCP Tile Production Facility



- Double lab at Argonne
- Designing layout of lab based on process requirements
- Build up facility over next couple years as process steps vetted

22 Apr 2011



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# ARRA Goal Summary -- Year 1

## ▶ Year 1

- Identify & characterize photoelectron emission properties of materials for photocathode development **complete**
- Demonstration of amplification with gain  $\geq 300$  with ALD-functionalized MCP **complete**
- Achieve differential time resolution  $< 10$  ps and space resolution  $\leq 1$ mm in vacuum with  $50\Omega$  transmission-line anode **complete**
- Upgrade existing collaboration vacuum transfer facilities to match 8"-square module assembly **just completing**
- Design including costing & interfacing with vendors of production sealed-glass tubes, for vacuum-transfer/assembly facility for 8"-square module **complete**
- Design prototype 2 channel ASIC with sampling  $\geq 20$  GSa/s, analog bandwidth  $\geq 1.5$ GHz, and capacitor-sampling-chain and timing blocks **complete**
- Demonstration of operational 8"-square photocathode **in progress at SSL**
- Demonstration of vacuum seal of 8"-square window to body **complete**
- Summary report on Year 1 progress including technical achievements and knowledge gained **complete**



# ARRA Goal Summary -- Year 2

## ▶ Year 2

- Demonstration of gain  $10^6$  and aging performance comparable to or better than commercial MCPs with pair of ALD-functionalized plates **complete**
- Development of MCP test facility capable of handling 8" plates **complete**
- Functionalization of 8"×8" glass capillary substrate with ALD **done; process optimization in progress**
- Design and costing of photocathode characterization facility **operational and continuing**
- Design and costing of 8" glass tile assembly facility **in progress**

Visit our web site for more information:

<http://psec.uchicago.edu>

("Blog" and "Library" links are a good starting place)



# Future Work

- ▶ Photocathode
  - Produce 8"×8" photocathode with  $QE \geq 25\%$  with acceptable dark current
  - Continue characterization survey of novel materials for photo/secondary emission
- ▶ Glass Substrate
  - Evaluate process economics for large picosecond timing & medical applications
  - Setup for multiple plate production optimized for ALD coating process & robust mechanical assembly
- ▶ Atomic Layer Deposition
  - Evaluate process economics for large picosecond timing & medical applications
  - Achieve single resolution out to 4 pe's
  - Continue characterization of materials for resistive and secondary emissive properties
- ▶ Testing
  - Transition to large volume testing
  - Continue to test innovations on small scale
- ▶ Simulation
  - Complete end-to-end simulation package
- ▶ Mechanical Assembly
  - Build quantity of 8"×8" tiles and 3×2 tile modules
  - Design & optimize assembly procedures
- ▶ Electronics
  - Design production generation clock distribution
  - Design production FPGA DAQ/control card
  - 6 Channel PSEC chip



# BACKUP SLIDES



# Improvements & Issues in Glass Capillary Arrays

## Issues:-

We still have linear striations inside the multifibers

There seem to be 4 types of multifiber

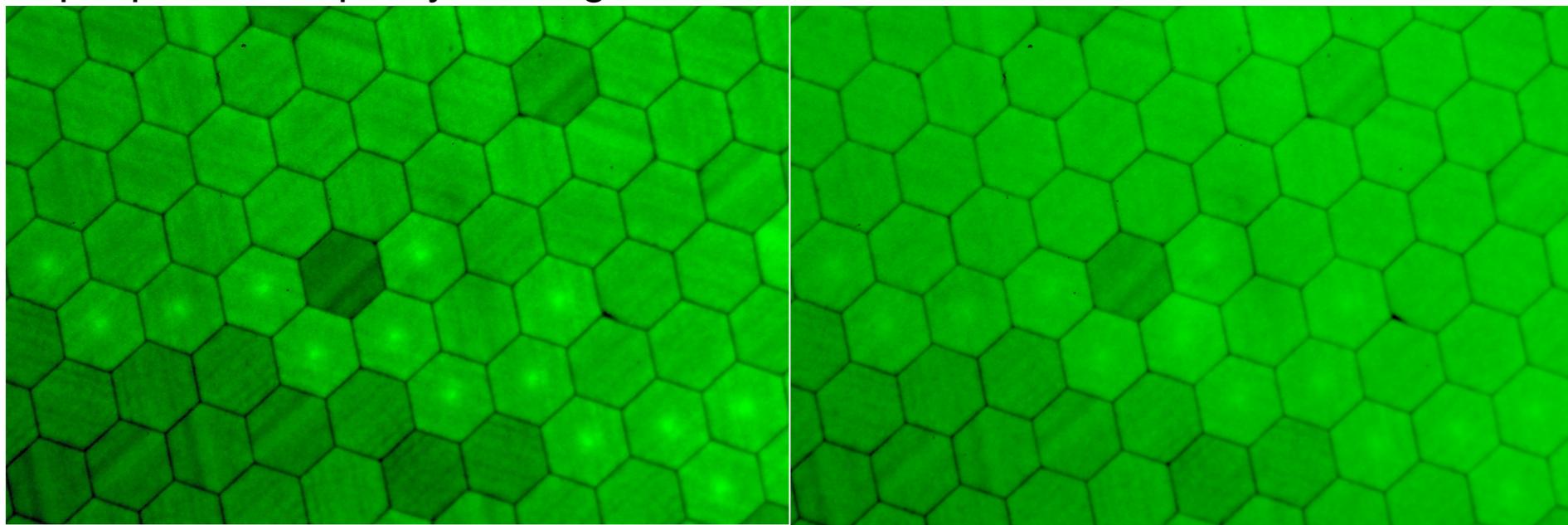
- Most are pretty good, low striation

- Some are darker – low gain – smaller open area ratio

- Some pretty good but with bright spot in middle

- 3 extra bright multifibers

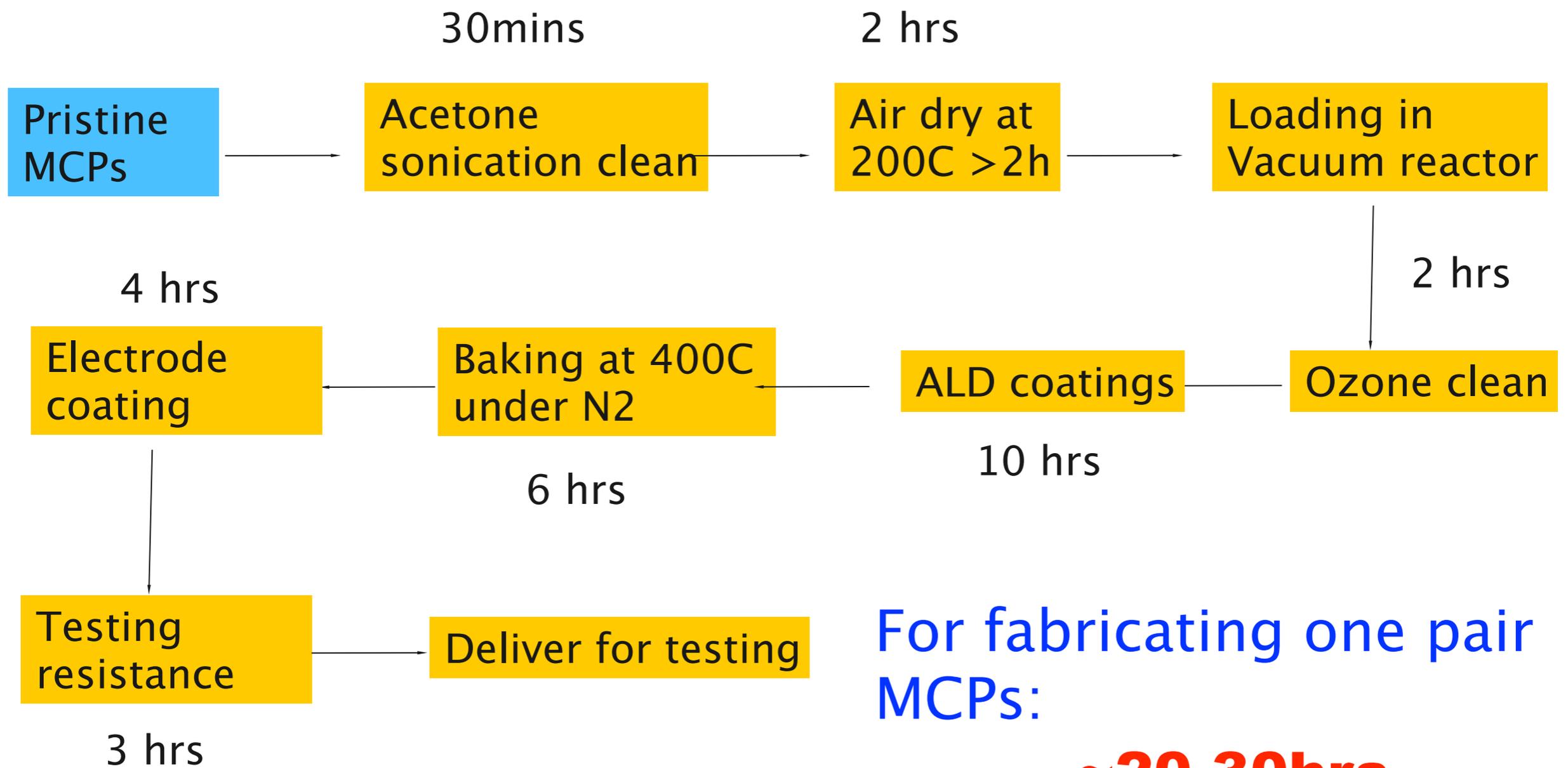
Triple points are pretty much gone, multifiber boundaries are thin and uniform!



800v MCP

1000v MCP

# General procedures for Fabrication of MCPs



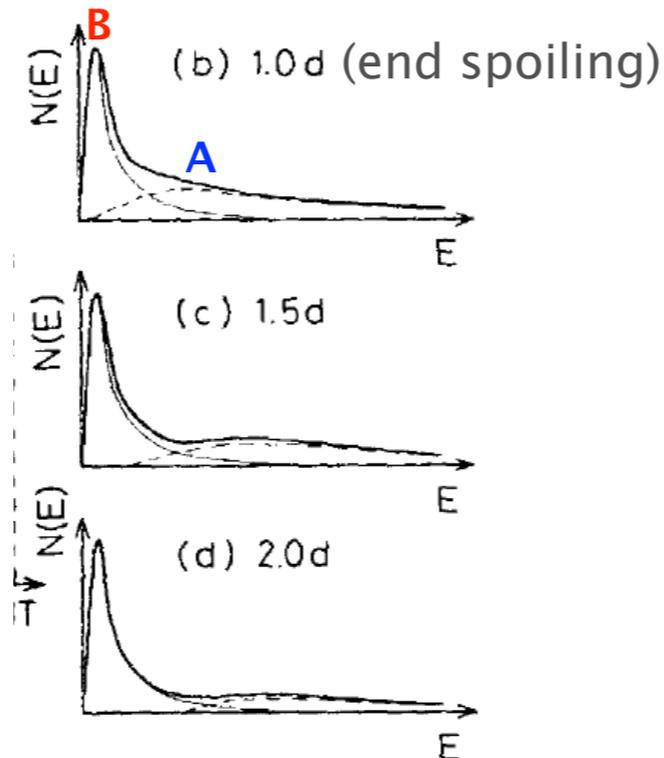
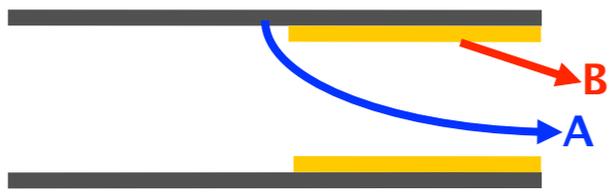
For fabricating one pair MCPs:

**~20-30hrs**

**if everything is right**

courtesy Qing Peng, Argonne ALD Group

# End-spoiling Details



- $N(E)$  becomes more narrow as end spoiling increases

$$\text{Gain} \sim (\text{SEC})^{(L/z)}$$

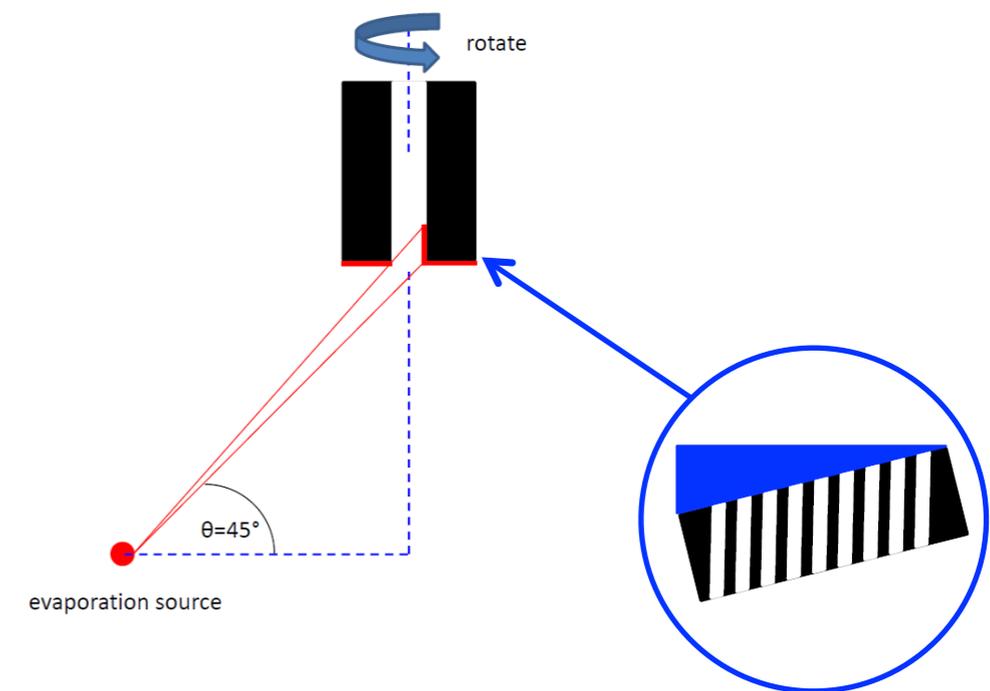
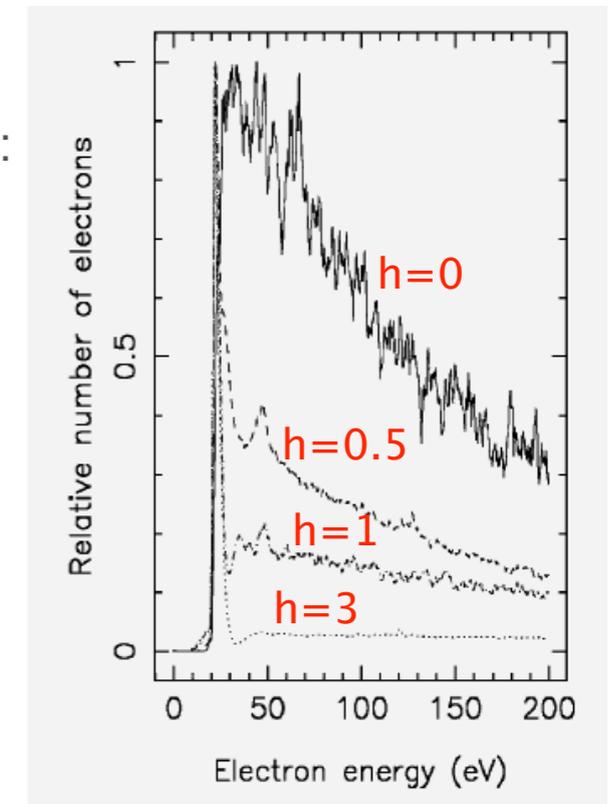
SEC=secondary electron coefficient

L=pore length

z=distance between collisions

$$\text{Gain} \sim (\text{SEC})^{(L/z)} \exp(-0.65h) \Rightarrow \text{Gain decreases}$$

Simulations:

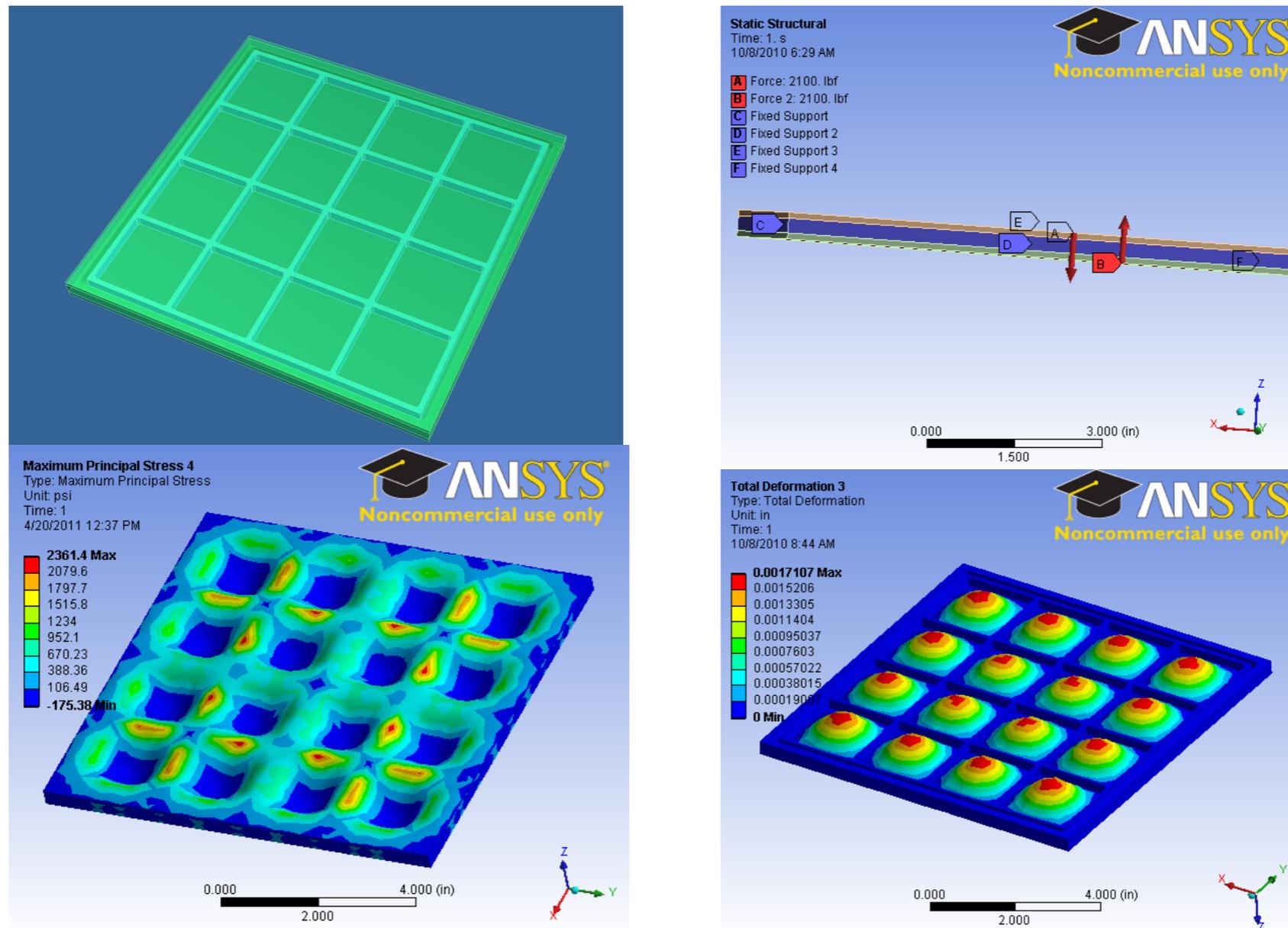


# Argonne Processed 20 $\mu$ m Substrates Summary of Parts

MCP 160												
A	C	L	M	N	O	R	S	T	U	V	W	X
	<b>Incc</b>											
Id		Resistive Layer		SEE Layer		Electroding			Annealing	Resistance		
Serial Number	Incom Batch No.	Chemistry	Thickness (Å)	Chemistry	Thickness (Å)	Material	Thickness (Å)	Location	End Spoiling	400C	Air Resistance (Mohm)	Vacuum Resistance (Mohm)
MCP 102	0A-47499	Chem-1	650	Al2O3	55	NiCr	2000	Over	1d	after electrode		
MCP 103	0A-47499	Chem-1	650	Al2O3	55	NiCr	2000	Over	1d	after electrode	40	360
MCP 112	0A-47499	Chem-1	650	Al2O3	55	NiCr	2000	Over	1d	no		
MCP 114	0A-47499	chem-2	800	Al2O3	55	NiCr	2000	Under	1d	no	100	112
MCP 116	0A-47499	chem-2	800	Al2O3	55	NiCr	2000	Under	1d	no		31
MCP 136	1A-31445	chem-2	800	Al2O3	55	NiCr	2000	Over	1d	before electrode	179	185
MCP 137	1A-31445	chem-2	800	Al2O3	55	NiCr	2000	Over	1d	before electrode	164	175
MCP 140	1A-31445	chem-2	850	MgO	75	NiCr	2000	Over	1d	before electrode	99	
MCP 143	1A-31445	chem-2	850	MgO	75	NiCr	2000	Over	1d	before electrode	86	
MCP 145	1A-31445	chem-2	900	MgO	75	NiCr	2000	Over	1d	before electrode	25	25
MCP 146	1A-31445	chem-2	900	MgO	75	NiCr	2000	Over	1d	before electrode	21	21
MCP 160	300-2734-G	chem-02	860	Al2O3	60	NiCr	2000	under	1d	no	55	40
MCP 161	300-2734-G	chem-02	860	MgO	80					before electrode		
MCP 162	300-2734-G	chem-02	860	MgO	80					before electrode		
MCP 166	300-2734-G	chem-02	860	MgO	80					no		
MCP 167	300-2734-G	chem-02	860	Al2O3	60					before electrode		
MCP 168	300-2734-G	chem-02	860	Al2O3	60					before electrode		

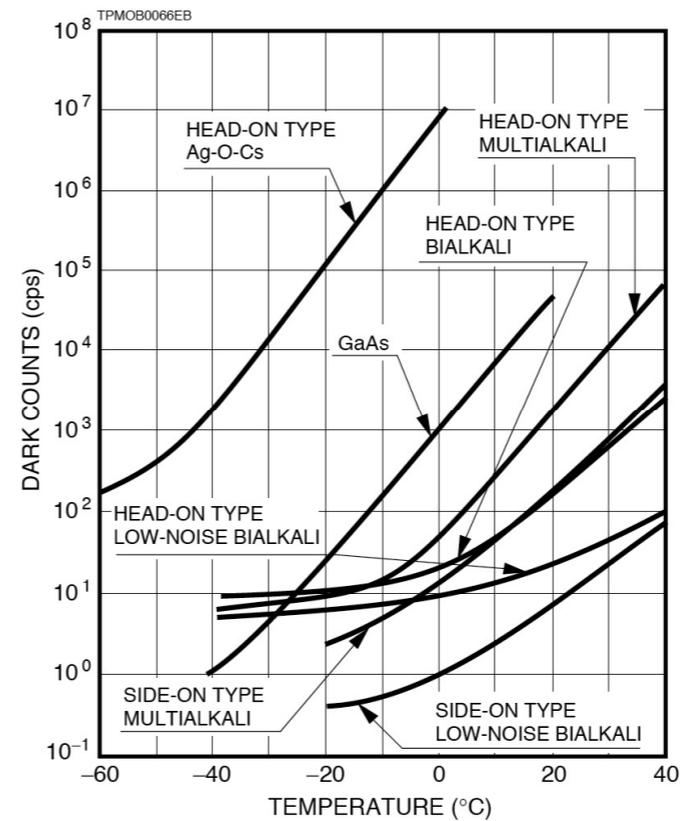
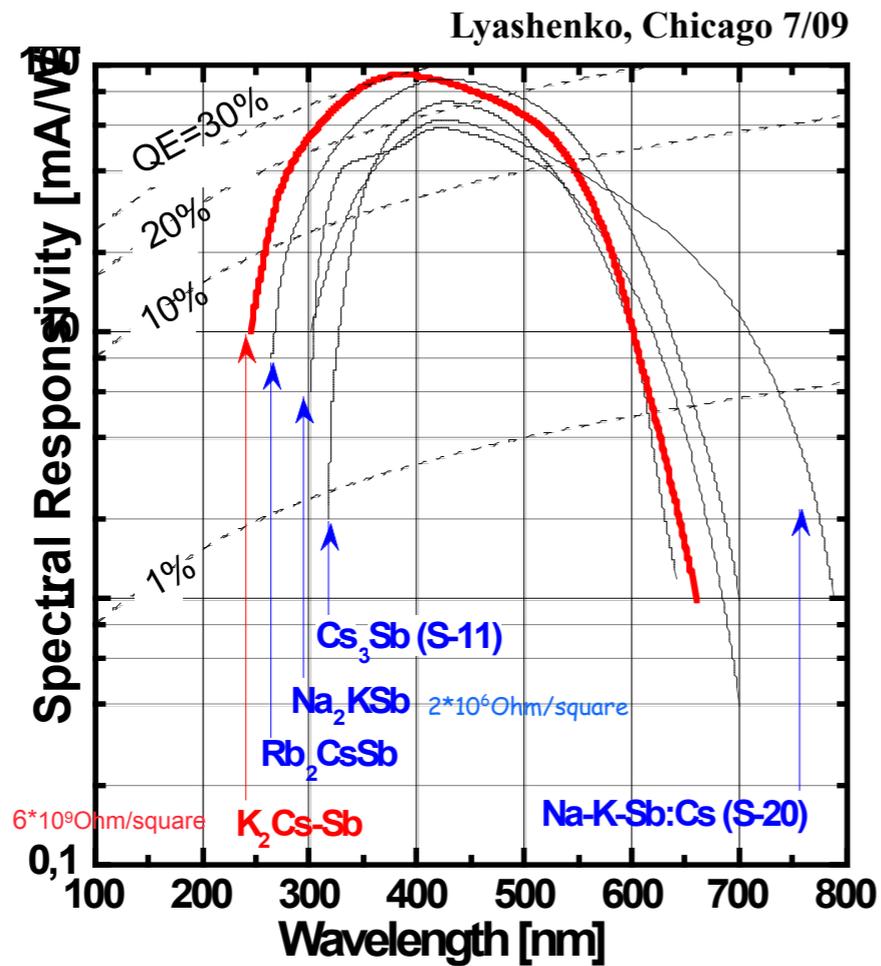
# FEA Analysis of Grid Spacer Loading

## Grid Spacer Stress Analysis based on 28 psi loading



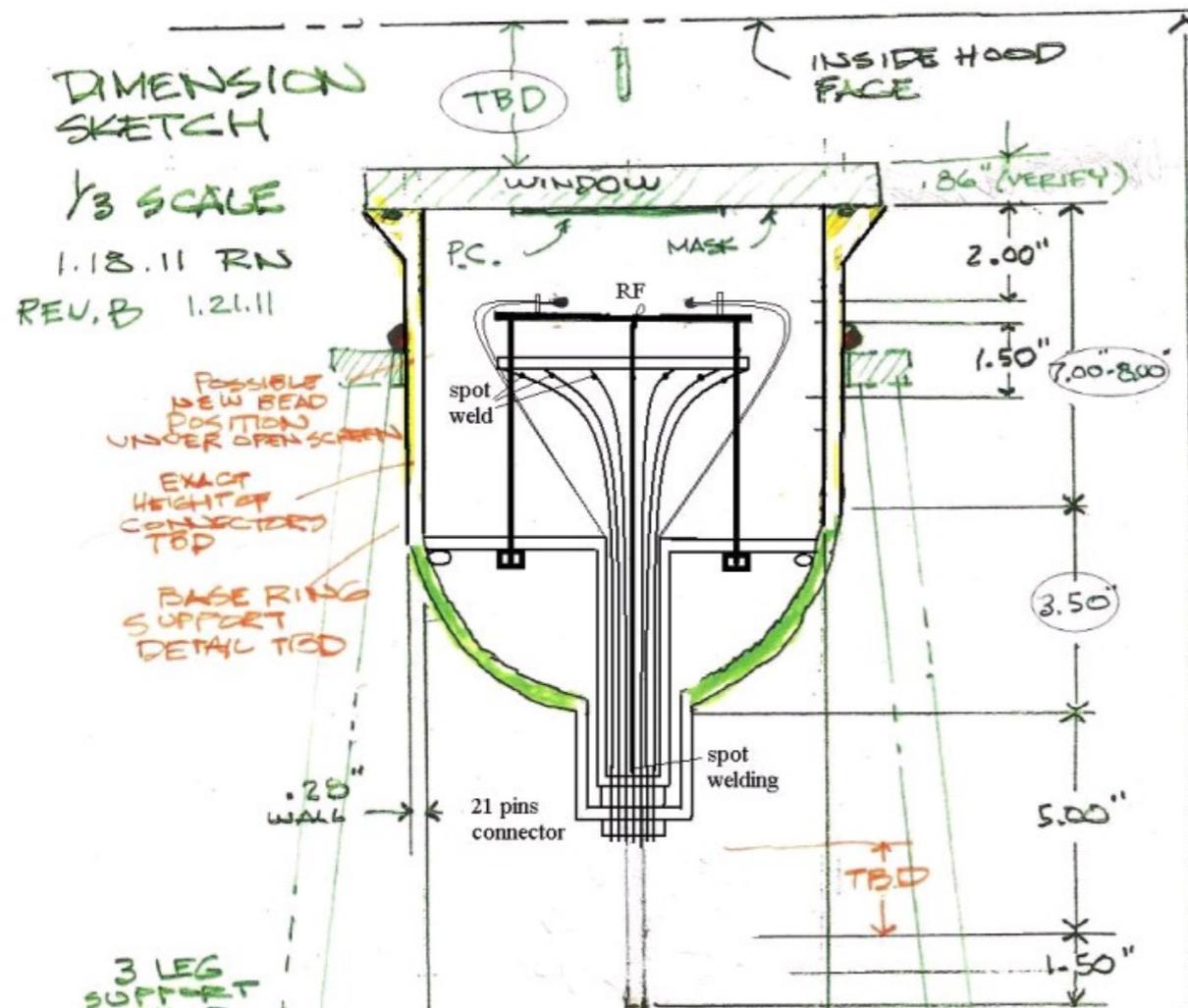
**Safety factor of 2.3 (actual bending vs. ultimate) - 350 psi compressive load thru stack**  
Maximum bending stress for B33 is 3626 psi

# Typical Bi-Alkali Cathode Characteristics

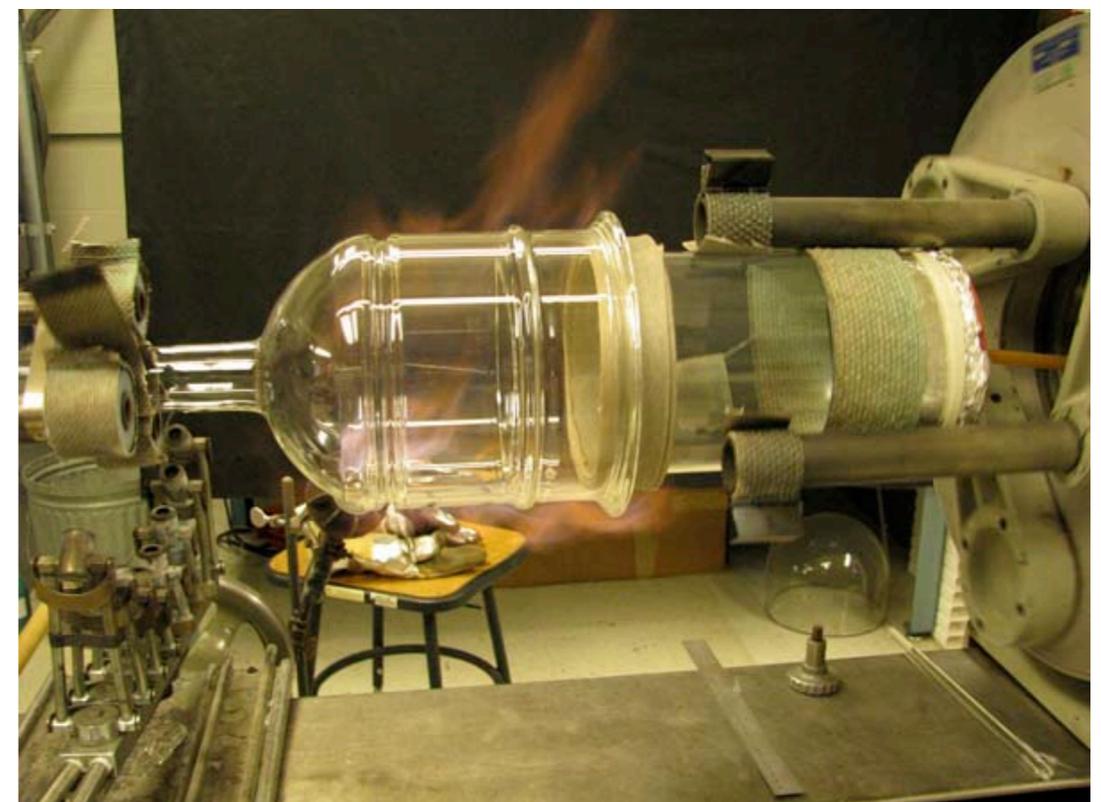


**Cathode Noise vs Temp  
expect 10,000 to 40,000  
events/sec for 8" tube bialkali!**

# Bialkali Photocathode -- Scale-Up to 4" Photocathode



Mount for alkali and Sb metal beads



"Chalice" fabrication in Argonne Glass Shop

# Chamber for Testing 8"×8" MCP Plates

